

## LIST OF DOCUMENTS CITED BY APPLICANT

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A-9183

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Applicant

Tarak A. RAILKAR et al.

Filing Date

Group

July 1, 2002

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## U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Sub-class	Filing Date
OK	AA 6,008,525	12/28/99	Barron et al.	257	629	
OK	AB 5,352,330	10/04/94	Wallace	156	643	
OK	AC 5,665,637	09/09/97	Chand	372	46	
OK	AD 4,406,053	09/27/83	Takasaki et al.	29	588	
OK	AE 5,139,606	08/18/92	Maki	156	643	
OK	AF 5,736,709	04/07/98	Neiheisel	219	121.61	
	AG					
	AH					
	AI					
	AJ					

## FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Sub-class	Translation
OK	AK 63-102918	05/07/88	Japan			Abstract
	AL					
	AM					

## OTHER (including author, title, date, pertinent pages, etc.)

OK	AN	N.C. Tien et al., "Surface adhesion reduction in silicon microstructures using femtosecond laser pulses", <u>Appl. Phys. Lett.</u> , 68 (2), 8 January 1996, pp. 197-199.				
	AO					
	AP					

Examiner

*Christy Horacek*

Date Considered

1/7/05

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.